

Title (en)
Device for radiating a substrate

Title (de)
Vorrichtung zum Bestrahlen eines Substrats

Title (fr)
Dispositif de rayonnement d'un substrat

Publication
EP 2192366 A3 20140101 (DE)

Application
EP 09171971 A 20091001

Priority
CH 18802008 A 20081201

Abstract (en)
[origin: EP2192366A2] The device has an elongated ultraviolet lamp (3) with a reflector (4) along a longitudinal axis (A), where the ultraviolet lamp is arranged in a housing (1). A cooling arrangement is provided for cooling the ultraviolet lamp by a cooling gas stream. Another cooling arrangement is provided for cooling the cooling gas stream by a fluid. Two units are provided with blowers for cooling the ultraviolet lamp, where the units blow transverse to the longitudinal axis. The latter cooling arrangement has cooling surfaces at the path of the cooling gas and dissipates heat outwards.

IPC 8 full level
F21V 29/02 (2006.01); **F26B 3/28** (2006.01)

CPC (source: EP)
B41F 23/0409 (2013.01); **B41F 23/0453** (2013.01); **F26B 3/28** (2013.01)

Citation (search report)

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Designated contracting state (EPC)
AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO SE SI SK SM TR

Designated extension state (EPC)
AL BA RS

DOCDB simple family (publication)
EP 2192366 A2 20100602; EP 2192366 A3 20140101; EP 2192366 B1 20160727; CH 700039 A1 20100615

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EP 09171971 A 20091001; CH 18802008 A 20081201